## Sheet 1 of 2 Received: 4-2-04

FORM PTO-1449			AT7	ATTY DOCKET NO. SERIAL NO.			,			
INFORMATION DISCLOSURE STATEMENT			10/816,356 Not Yet Assigned			Í				
				APPLICANT(S): Woelk et al.						
				FILING DATE; ART UNIT: 2813						
				Herewith 04/02/2004 Not Yet Assigned						
UNITED STATES PATENT DOCUMENTS										
EXAM.	·	DOCUMENT					SUB	FIL.		
INITIAL		NUMBER	DATE		NAME	CLASS	CLASS	DATE IF		
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J.N.J.	AA	2,444,270	06/29/1948		E. Rochow			•		
S.W.S.	AB	3,446,824	05/27/1969		K. Moedritzer					
S.W.S	AC	4,506,815	03/26/1985		Melas et al.					
J.W.S.	AD	3,470,220	09/30/1969		Moedritzer et al.					
2W.8.	AE	5,120,394	06/09/1992		Mukai					
Sollie.	AF	5,502,227	03/26/1996		Kanjolia et al.					
A.W.S.	AG	5,755,885	05/26/1998		Mikoshiba et al.					
Silli	AH	6,099,903	08/08/2000		Kaloyeros et al.					
INZ.	AI	6,214,729	04/10/2001		Uhlenbrock et al.			<u>'</u>		
IWL.	AJ	6,238,734	05/29/2001		Senzaki et al.					
S.W.L.	AK	6,306,217	10/23/2001		Uhlenbrock et al.					
I Wisi	AL	6,391,803	05/21/2002		Kim et al.					
I.W.S.	AM	6,444,038	09/03/2002		Rangarajan et al.					
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J.W.Z.	AP	6,492,711	12/10/2002		Takagi et al.					
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ZW.S.	AR	6,514,886	02/04/2003		U'Ren					
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8.W.Z.	AT	2003/0111013	06/19/2003		Oosterlaken et al.					
Examiner:	tethen	W. Smoo	t		Date: February	20,	200	6		

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				APPLICANT(S): Woelk et al.						
				FILING DATE: ART UNIT: 2813 Herewith 04/02/2004 Not Yet Assigned						
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	BA	626,398	04/15/1946	· U	nited Kingdom	<del></del>				
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LN.S.	CC	Hoffman et al., "Plasma-enhanced chemical vapor deposition of silicon, germanium, and tin nitride thin films from metalorganic precursors", J. Vac. Sci. Technol. A 13(3), May/Jun 1995, pp. 820-825.								
S.W.S.	CD	O. Johnson, "The Germanes and Their Organo Derivatives", Chem. Rev. 1951, 48, 259, pp. 259-297.								
I.W.S.	CE	Kidd et al., "Germanium-73 Nuclear Magnetic Resonance Spectra of Germanium Tetrahalides", Journal of American Chemical Society, 95:1, January 10, 1973, pp. 88-90.								
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INFORMATION DISCLOSURE STATEMENT				1898	10/816,356					
INFURVIATIO	N DISCL	1		APPLICANT(S): Shenai-	Khatkhat	e et al.				
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2/1/2	AB	3,985,590	10/12/1976	Mason		_				
TIJŽ.	AC	4,720,561	01/19/1988	Bradley et al.						
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X 1.1 V.	AH	2004/0259333 A1	12/23/2004	Tomasini et al.		_				
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